

-<u>1</u>G.3

INSPECTION

PROCESS GROUP A

INSPECTION

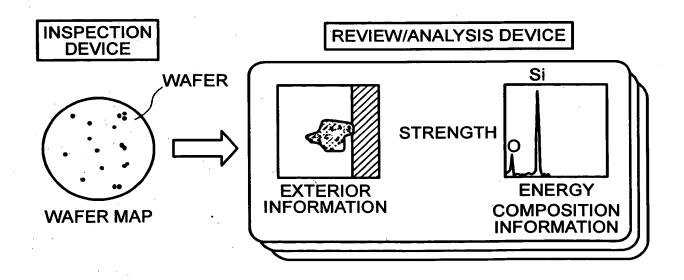
INSPECTION

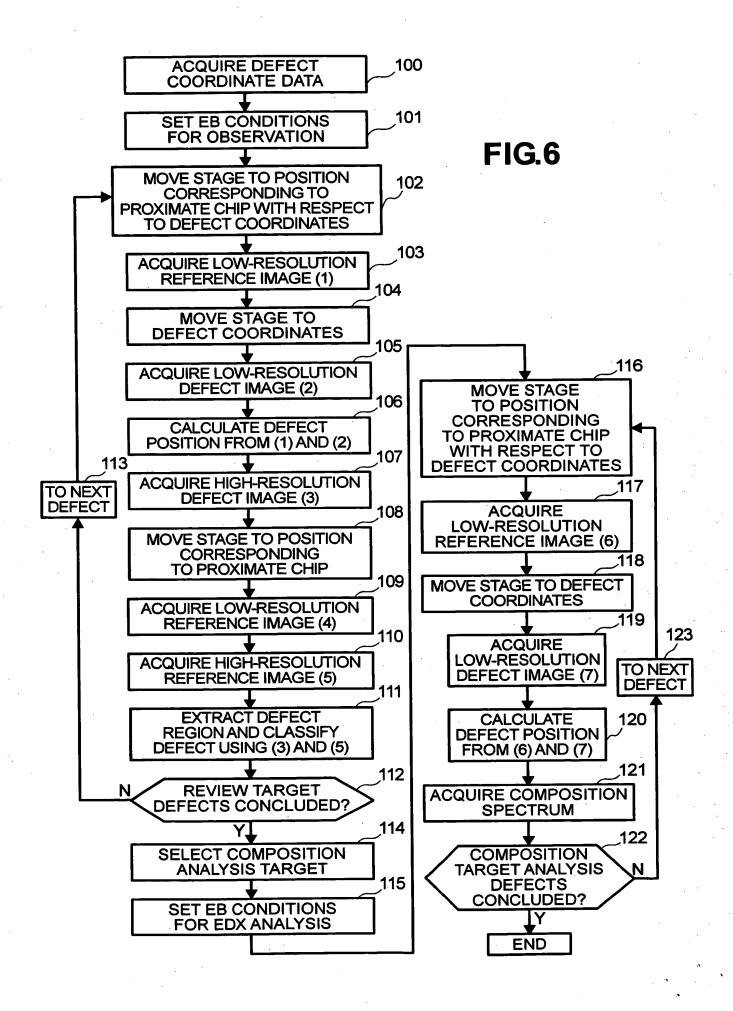
NORMAL RANGE

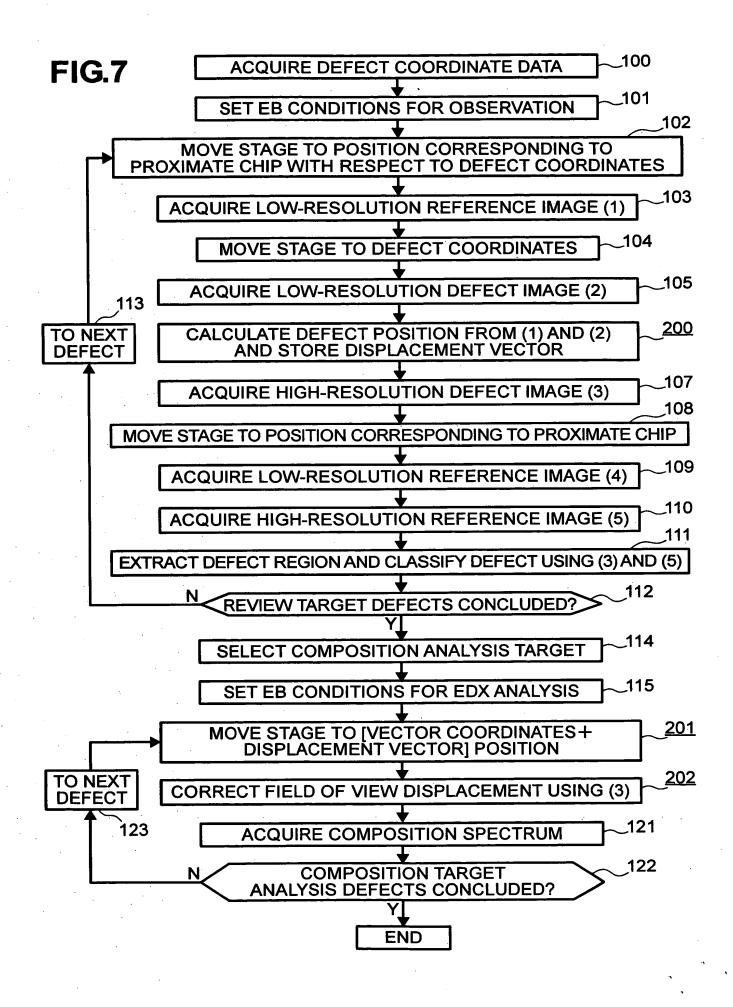
PROCESS GROUP B

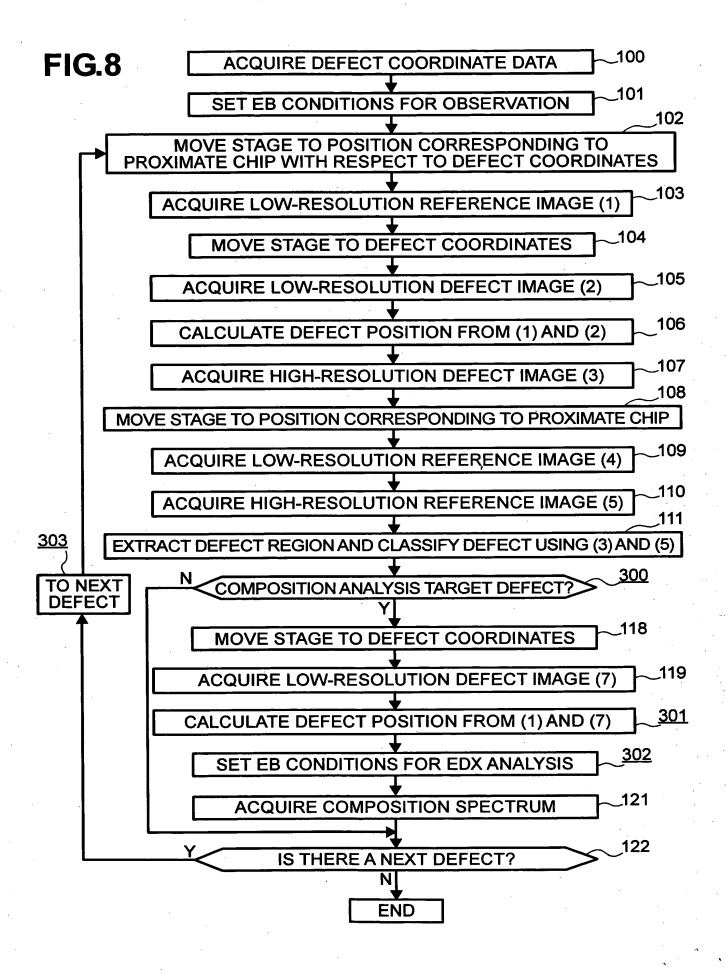
PROCESS GROUP B

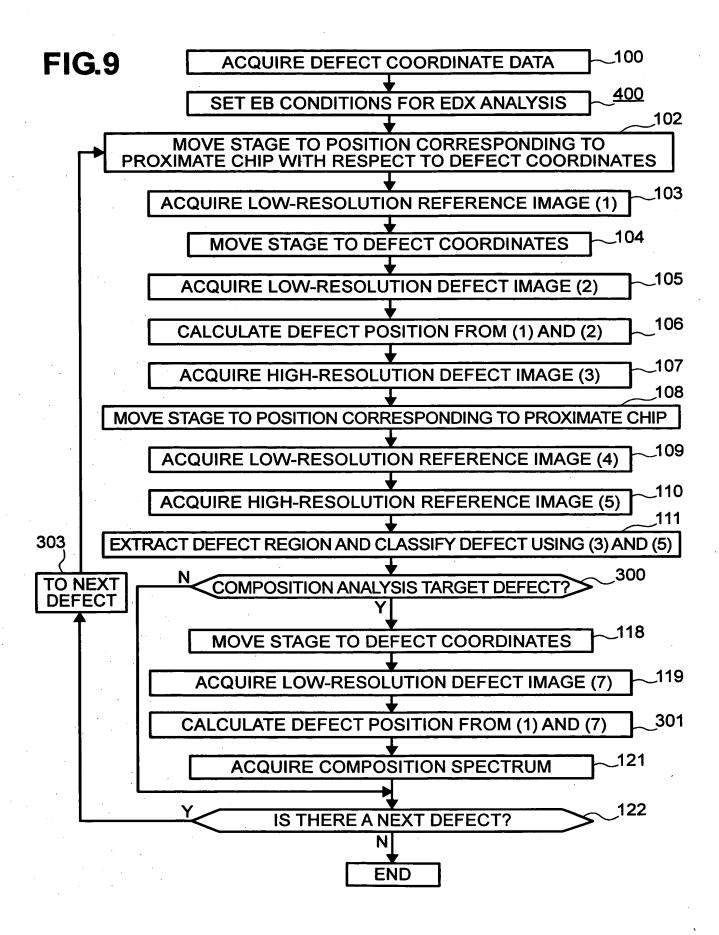
FIG.5



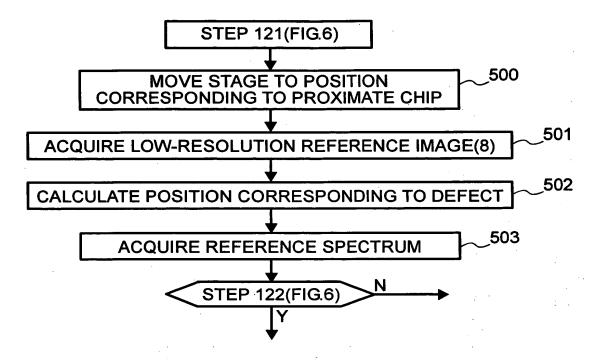




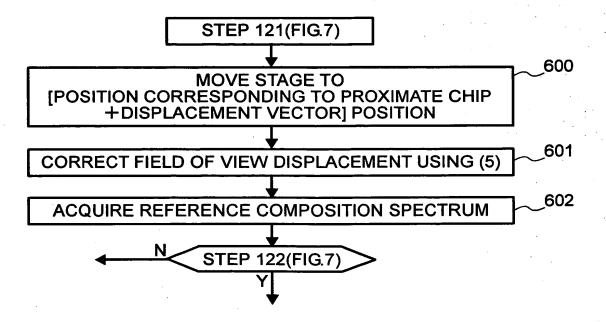




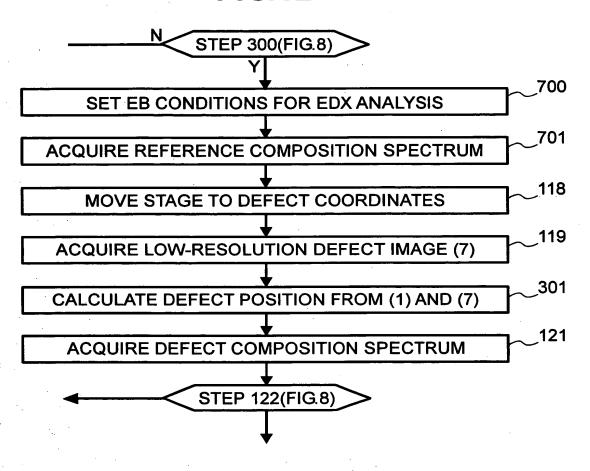
**FIG.10** 



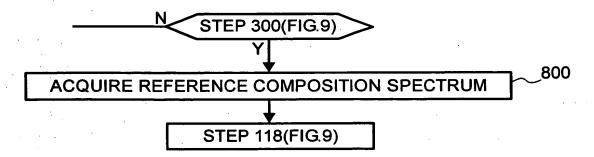
**FIG.11** 



**FIG.12** 



**FIG.13** 

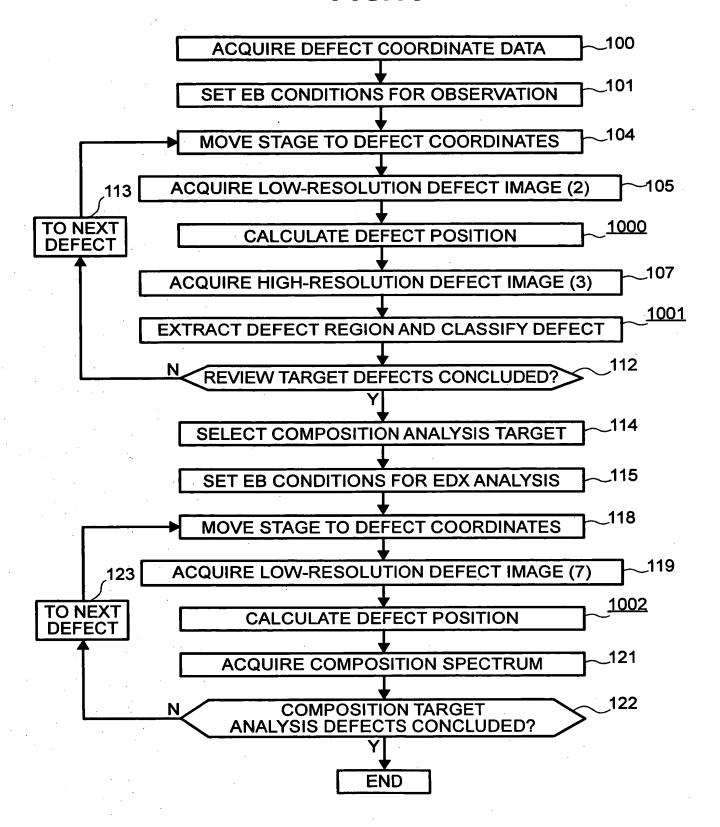


REFERENCE SPECTRUM EB IRRADIATION POSITION LINEAR PATTERN **LINEAR PATTERN** POSITION CORRESPONDING TO DEFECT LOW-RESOLUTION REFERENCE IMAGE FIG.14C FIG.14B **TEMPLATE** DEFECT 902 900 901 LOW-RESOLUTION REFERENCE IMAGE TEMPLATE CENTER INCLUDED IN REGION SHOWING COINCIDENCE THAT CAN BE REGARDED AS SAME PATTERN AND ACQUIRE REFERENCE **LOW-RESOLUTION DEFECT IMAGE JSE, AS EB IRRADIATION POSITION** TEMPLATE MATCHING IN **ACQUIRE TEMPLATE IN** FIG.14A

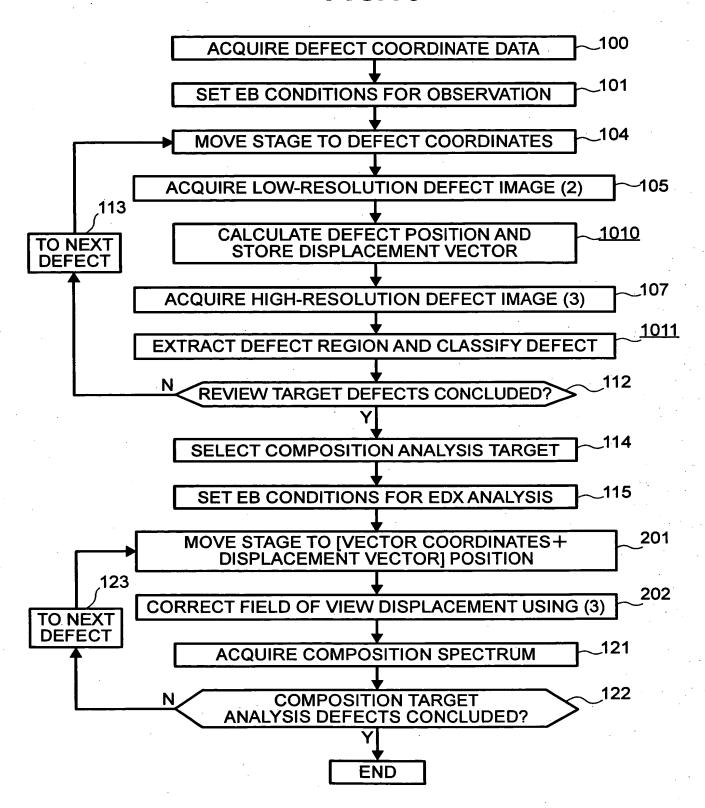
LOW-RESOLUTION DEFECT IMAGE

COMPOSITION SPECTRUM

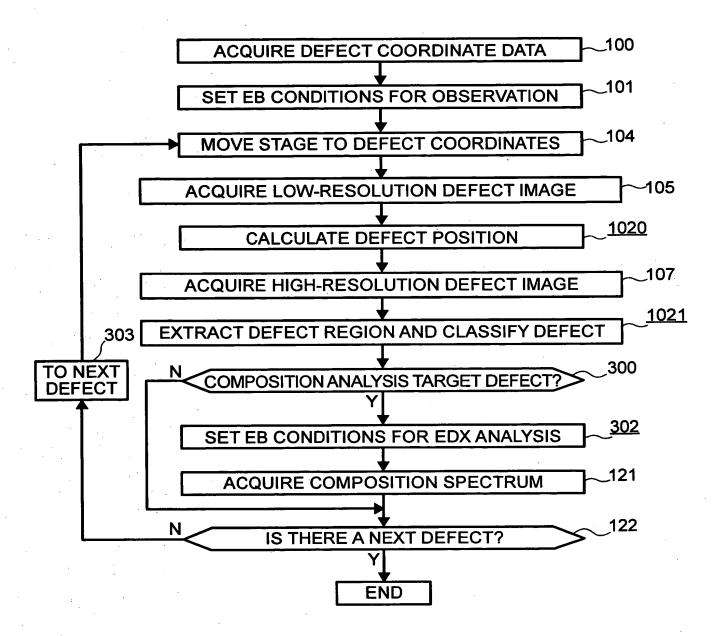
**FIG.15** 



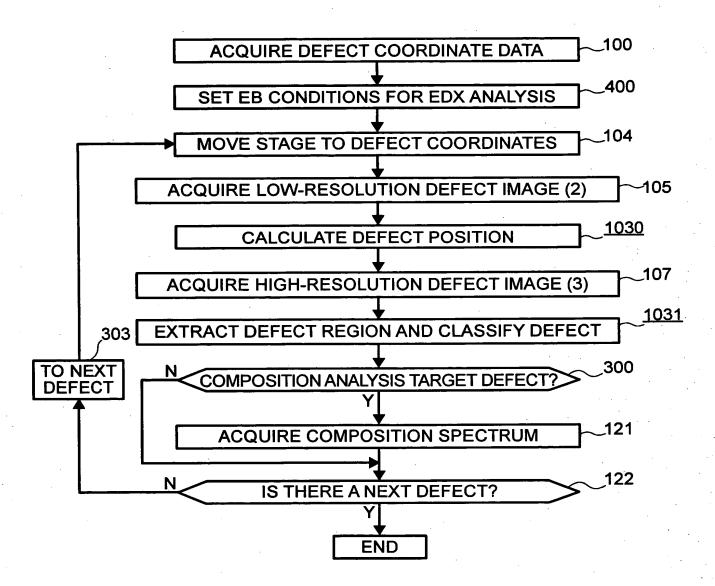
**FIG.16** 



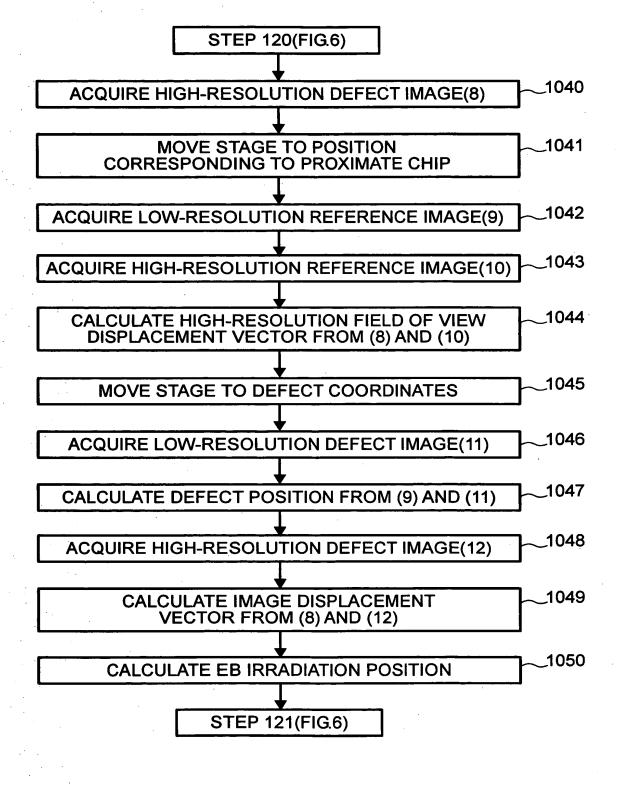
**FIG.17** 



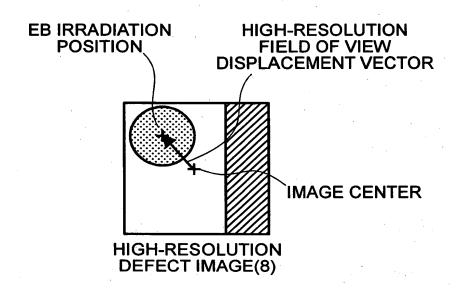
**FIG.18** 

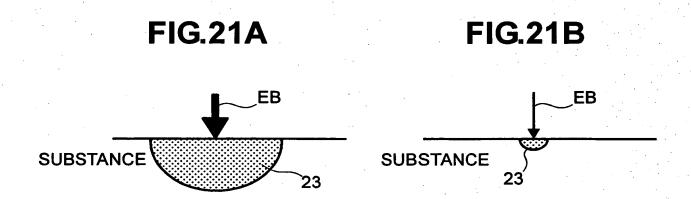


**FIG.19** 

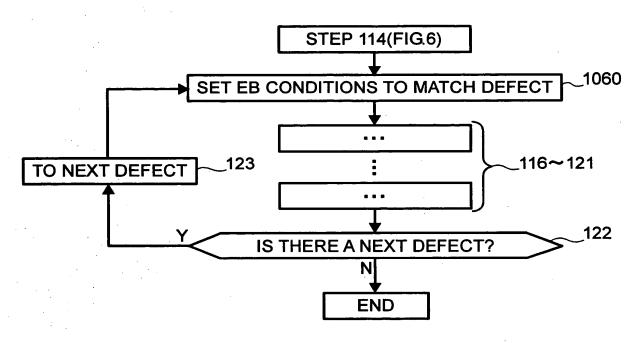


**FIG.20** 

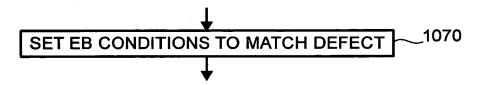


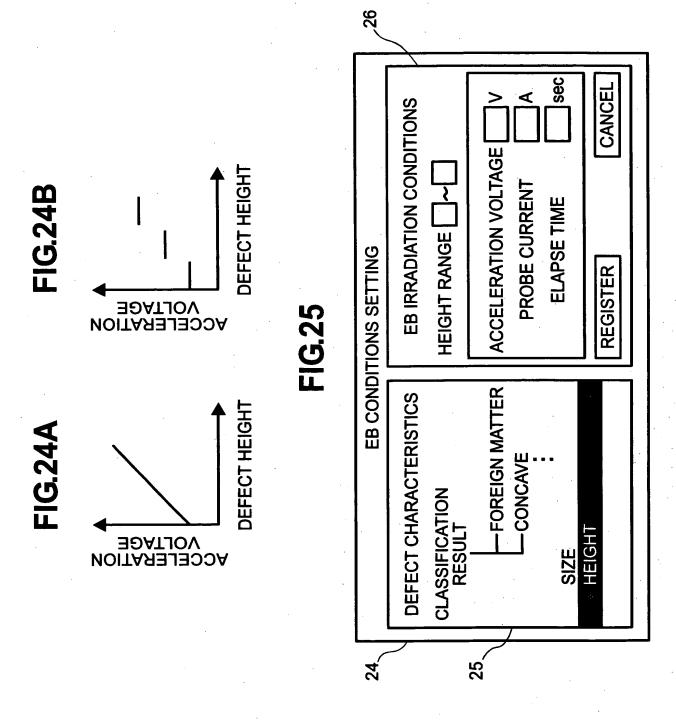


**FIG.22** 



**FIG.23** 





**FIG.26** 

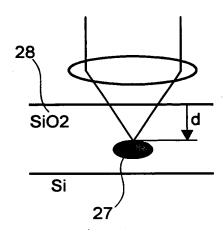
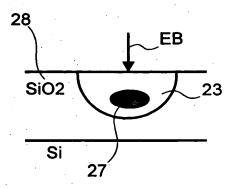
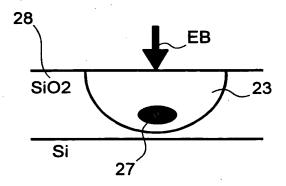
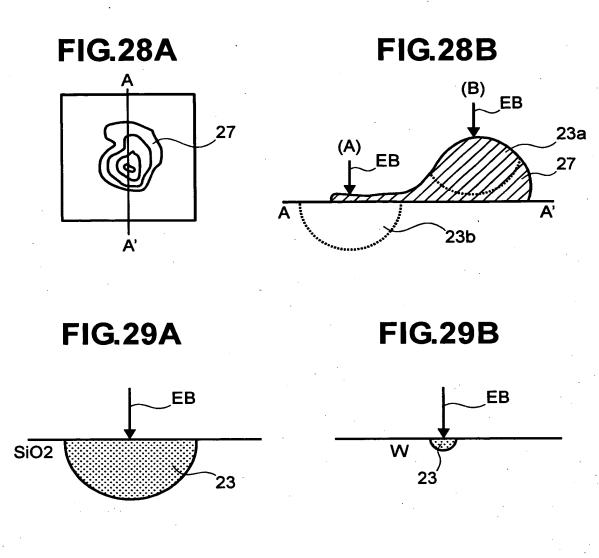


FIG.27A

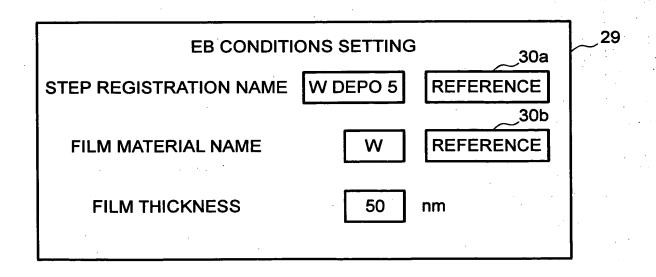
FIG.27B







**FIG.30** 



**FIG.31** 

